

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Tadahiro OHMI et al
Title: METHOD OF MANUFACTURING A SEMICONDUCTOR DEVICE
AND METHOD OF ETCHING AN INSULATING FILM
Appl. No.: 10/588,698
Filing Date: 08/08/2006
Examiner: Caridad Everhart
Art Unit: 2895
Confirmation Number: 9929

STATEMENT OF SUBSTANCE OF INTERVIEW

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In accordance to 37 C.F.R. § 1.133, submitted herewith is a record of the substance of the interview on February 18, 2009, with Examiner Caridad Everhart, regarding the above-captioned application.

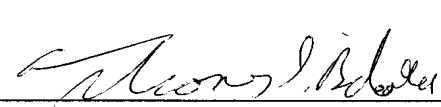
The interview summary of the substance of the interview on February 18, 2009 is accurate. This statement is being submitted within one (1) month of the mailing date of February 26, 2009, of the Interview Summary and is therefore a timely response.


Applicants acknowledge the Supplemental Notice of Allowance issued on February 26, 2009.

Respectfully submitted,

Date March 25, 2009

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